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Analytical Services & Consulting

Materialcharakterisierung Materials Characterisation

### A10561 **ToF-SIMS Analysis Particles** on a Cu Detection Screen

Intellect Technologies

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\*: see also disclaimer section at the end of this report







#### Sample Description and Analytical Task

- On a Cu detection screen splash lines which origin from the explosion of an anode are observed.
- Additionally, particles can be found close to the splash lines.
  The chemical composition (including isotopic ratios) is of interest in order to identify the origin of the particles.
- By means of SEM/EDX and Auger analysis one particle was found to contain Pb, Fe, Si, O, C, Al and possibly Au. The anode mainly contains Cu.
- Now, the particle should again be analyed using Time-of-Flight Secondary Ion Mass Spectrometry (ToF-SIMS) because of the higher sensitivity and the possibility to obtain information in the isotopic patterns of the elements found.



#### Sample Description and Measurements Performed

- Two particles of sample 232 were analysed:
  - the particle which was analysed previously by SEM/EDX and Auger spectroscopy ("particle 1")
  - a particle close to a distinct splash line which was not analysed before ("particle 2")
- First the surface composition of both particles was analysed by means of ToF-SIMS imaging. For particle 1 additionally the chemical composition in deeper layers was probed. Ion sputtering was used to get access to the deeper layers.

### **ToF-SIMS Fundamentals**



#### Characteristics of ToF-SIMS:

- The chemical composition of surfaces can be probed by means of Time of Flight Secondary Ion Mass Spectrometry (ToF-SIMS). The technique provides information on the atomic and molecular composition of the uppermost 1 - 3 monolayers with sensitivities at ppm level and lateral resolutions down to 100 nm.
  - ToF-SIMS is not an inherently quantitative technique because the detected intensities depend on the chemical composition of the ambient material ("matrix effect"). Semi-quantitative information can be obtained if the chemical environment of the samples to be compared is similar.

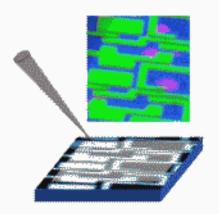
### **ToF-SIMS: Imaging**

#### Explanation



#### Imaging:

For acquisition of mass resolved secondary ion images (imaging, chemical mapping) a usually focused primary ion beam is used to probe the surface of interest. For each pixel addressed a complete spectrum is recorded. The intensities of secondary ion signals of interest are colour coded resulting in a mass resolved intensity map of the lateral distribution of secondary ion emission positions.



- Fields of view of up to 500x500 µm² can be analysed by rastering of the primary ion beam. Larger areas (500x500 µm² ... 9x9 cm²) can be analysed by an additional movement of the sample stage ("stage raster").
- The lateral resolution is 3-5 µm for routine analysis at full mass resolution and 300 - 500 nm at nominal mass resolution.

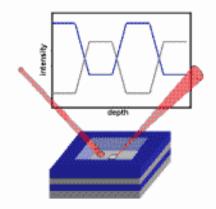
### **ToF-SIMS: Depth Profiling**

#### Explanation



#### Depth Profiling:

Depth profiles are acquired in order to investigate the chemical composition of a solid as a function of depth. In ToF-SIMS two different ion beams are used for data acquisition. A so-called sputter beam (e.g. O<sub>2</sub>+ or Cs+) is applied to erode the sample while a 2<sup>nd</sup> ion beam (analysis beam e.g. Au+) is used for a chemical characterisation of the resulting crater bottom. In most cases depth profiles only show the distribution of elements



because the massive sample erosion causes a destruction of molecular structures. In selected cases also organic information can be gained. Although the resulting intensities are not inherently quantitative a comparing semi-quantitative analysis of chemically similar samples is possible after a suited normalisation.



Measurement Conditions (Surface Imaging)

- Instrumentation:
  - IONTOF "TOF.SIMS 5"
- Analytical Conditions:

lon / Energy: Bi<sub>1</sub><sup>+</sup>, 25 keV

Mode: bunched mode

(high mass resolution,

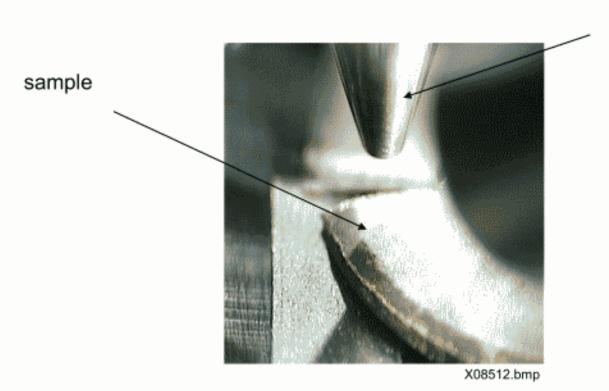
focus approx. 3 µm)

Analysis Current: 0.2 pA

Area: 156 x 156 μm<sup>2</sup>



Optical Image of Sample 232 (Overview)



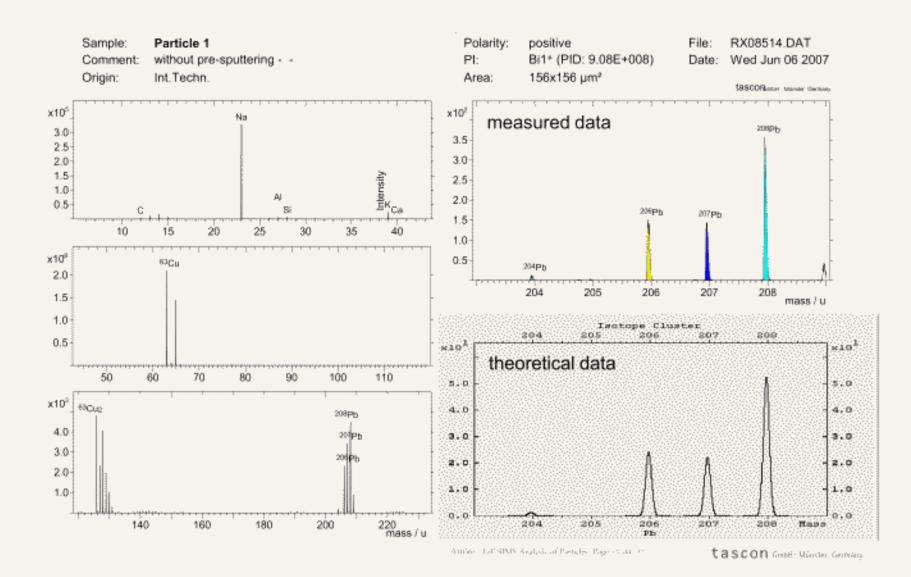
secondary ion extractor



Optical Image of Sample 232 (Detail View, Particle 1)

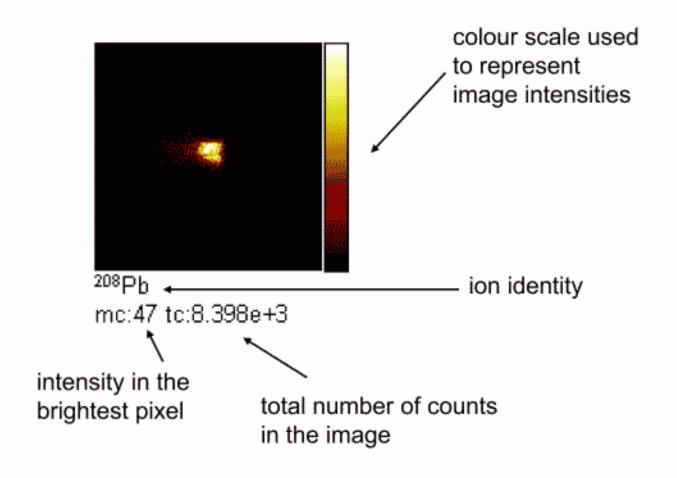
Field of View approx. 700 x 850 µm<sup>2</sup> splash line X08513.bmp

Reconstructed Spectrum from 156 x 156 µm² (Incl. Particle)



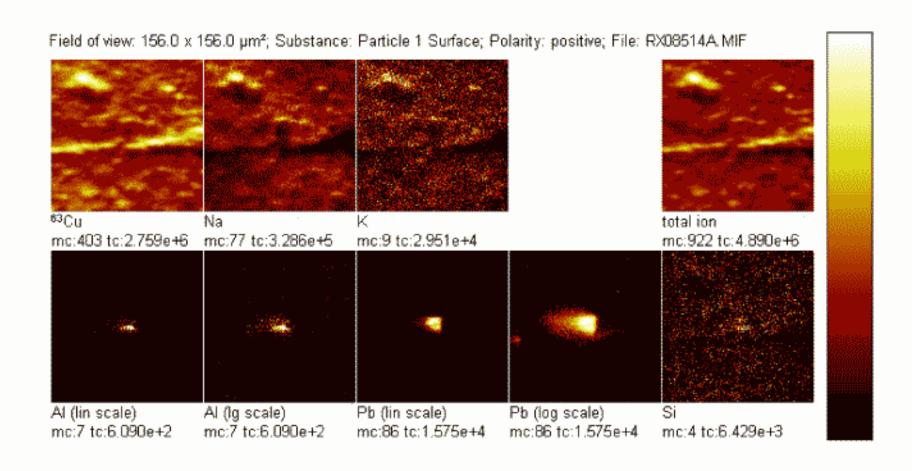


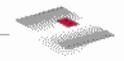
#### Explanation of Image Plots





Image, Positive Secondary Ion Polarity





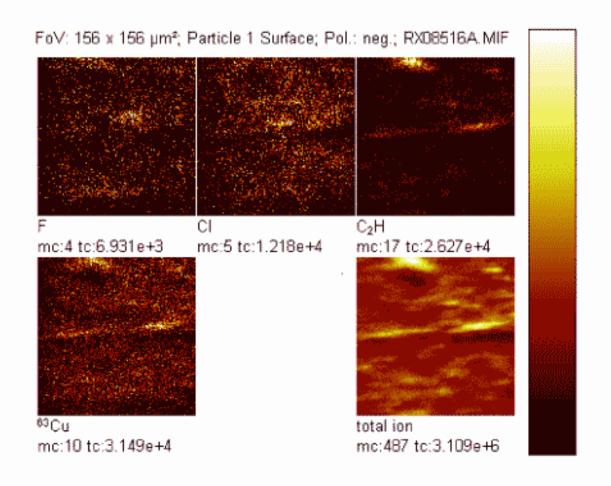
Correlation Analysis: 3 Colour Overlay

field of view: 156 x 156 µm<sup>2</sup> Pb Αl Cu

data taken from RX08514a.MIF



#### Image, Negative Secondary Ion Polarity





Results of Surface Imaging (Bunched Mode)

- The following elements were detected in the analysed area of 156 x 156 µm<sup>2</sup>:
  - H, Li, B, C, O, Na, Mg, Al, Si, K, Ca, Ti, Fe, Ni, Cu, Zn, Ag, Pb
- Within the particle mainly Al, Si and Pb are found. Additionally, F and Cl can be detected.
- The lateral distribution of Al and Pb show a halo in splash direction.
- The splash line mainly consists of Cu. Na and K are not found in the splash line. However, they can be detected on the Cu surface of the detection screen. Additionally, organic material is detected.
- The isotopic distribution of the elements is in good agreement with the natural occurring isotopic ratios. However, the intensity of most elements is too weak to show deviations of less than 20%.



Measurement Conditions (Surface Imaging)

- Instrumentation:
  - IONTOF "TOF.SIMS 5"
- Analytical Conditions:

Ion / Energy: Bi<sub>1</sub><sup>+</sup>, 25 keV

Mode: burst alignment mode

(nominal mass resolution,

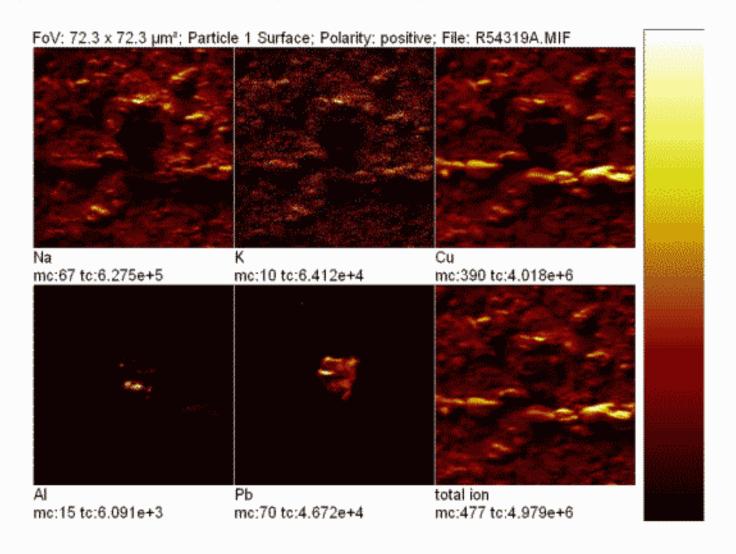
focus approx. 300 nm)

Analysis Current: 0.2 pA

- Area: 72 x 72 μm²



#### Image, Positive Secondary Ion Polarity





Correlation Analysis: 3 Colour Overlay

Pb Αl Cu

data taken from R54319a.MIF

field of view: 72 x 72 µm<sup>2</sup>



Measurement Conditions (Surface Imaging)

Instrumentation:

IONTOF "TOF.SIMS 5"

Analytical Conditions:

Pre-Sputtering: O<sub>2</sub><sup>+</sup>, 2 keV; 560 nA on 500 x 500 μm<sup>2</sup>

Sputter Time: 2 minutes

Ion / Energy: Bi<sub>1</sub>+, 25 keV

Mode: burst alignment mode

(nominal mass resolution,

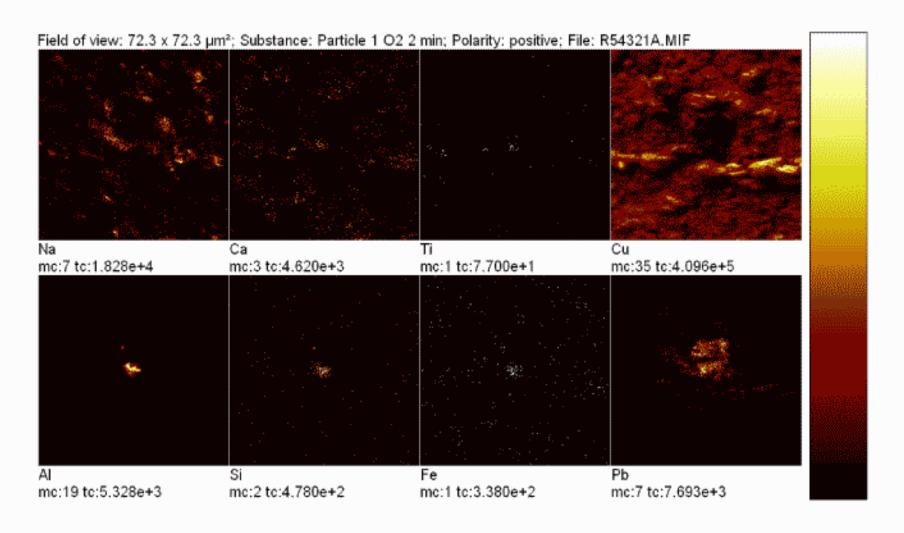
focus approx. 300 nm)

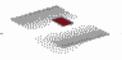
Analysis Current: 0.2 pA

- Area: 72 x 72 μm<sup>2</sup>



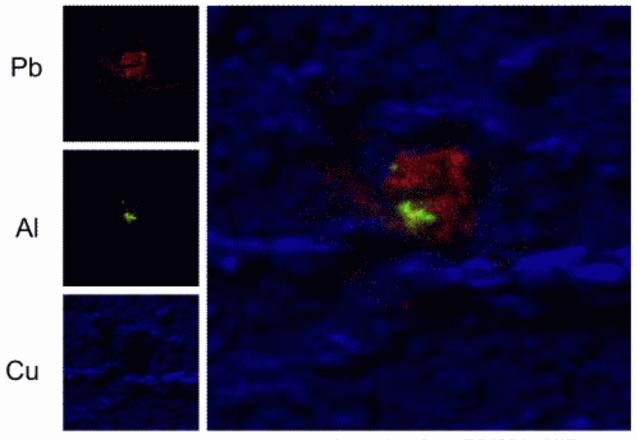
#### Image, Positive Secondary Ion Polarity





Correlation Analysis: 3 Colour Overlay

field of view: 72 x 72 µm<sup>2</sup>



data taken from R54321a.MIF



Measurement Conditions (Surface Imaging)

Instrumentation:

IONTOF "TOF.SIMS 5"

Analytical Conditions:

Pre-Sputtering: O<sub>2</sub><sup>+</sup>, 2 keV; 560 nA on 300 x 300 μm<sup>2</sup>

Sputter Time: 4 minutes (total: 6 minutes)

Ion / Energy: Bi<sub>1</sub>+, 25 keV

Mode: burst alignment mode

(nominal mass resolution,

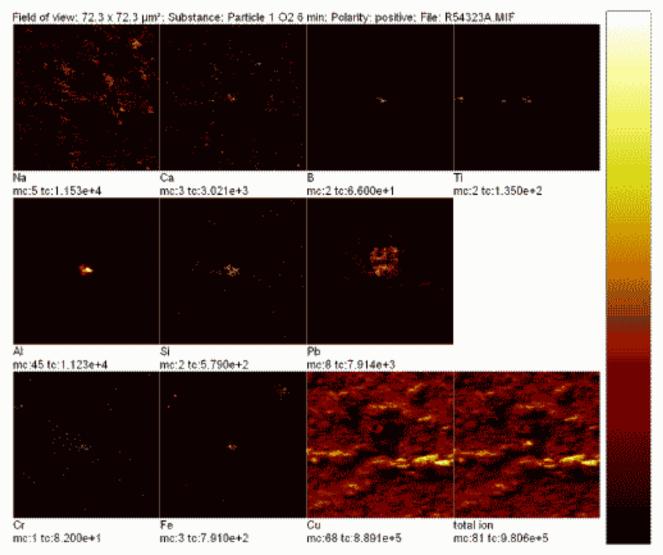
focus approx. 300 nm)

Analysis Current: 0.2 pA

- Area: 72 x 72 μm²



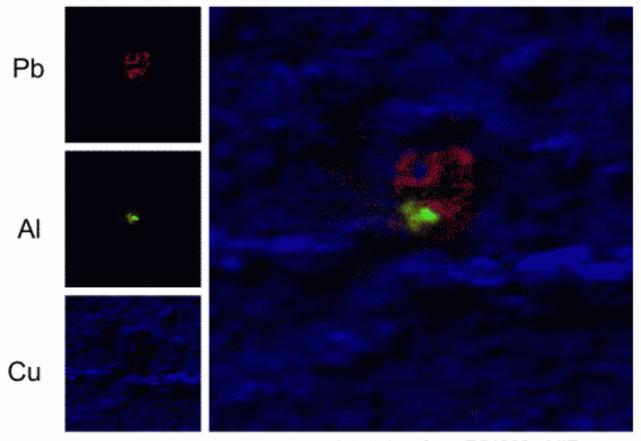
#### Image, Positive Secondary Ion Polarity





Correlation Analysis: 3 Colour Overlay

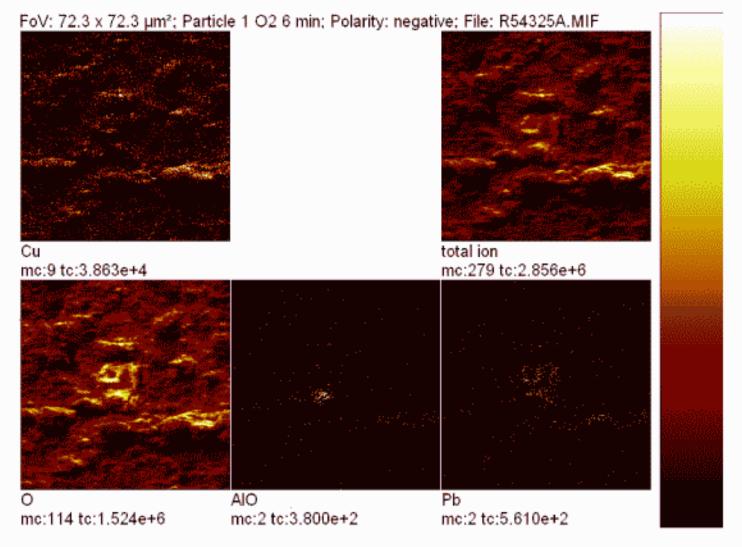
field of view: 72 x 72 µm<sup>2</sup>



data taken from R54323a.MIF



#### Image, Negative Secondary Ion Polarity





Measurement Conditions (Surface Imaging)

- Instrumentation:
  - IONTOF "TOF.SIMS 5"
- Analytical Conditions:

- Pre-Sputtering: O<sub>2</sub>+, 2 keV; 560 nA on 300 x 300 μm<sup>2</sup>

Sputter Time: 10 minutes (total: 16 minutes)

Ion / Energy: Bi<sub>1</sub>+, 25 keV

Mode: burst alignment mode

(nominal mass resolution,

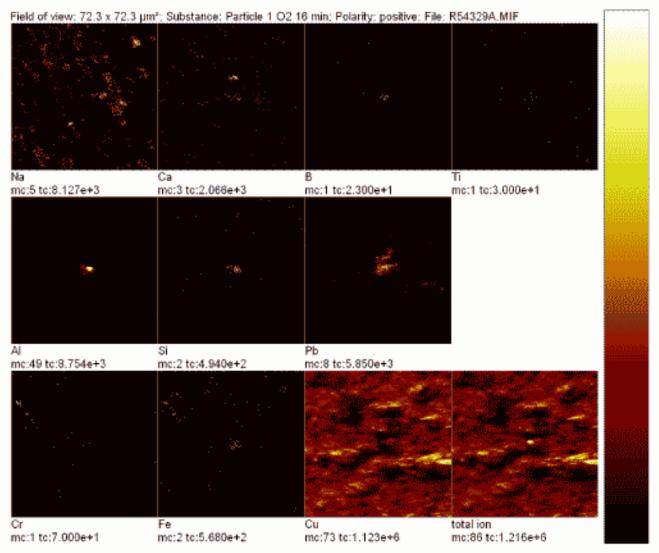
focus approx. 300 nm)

Analysis Current: 0.2 pA

- Area: 72 x 72 μm<sup>2</sup>



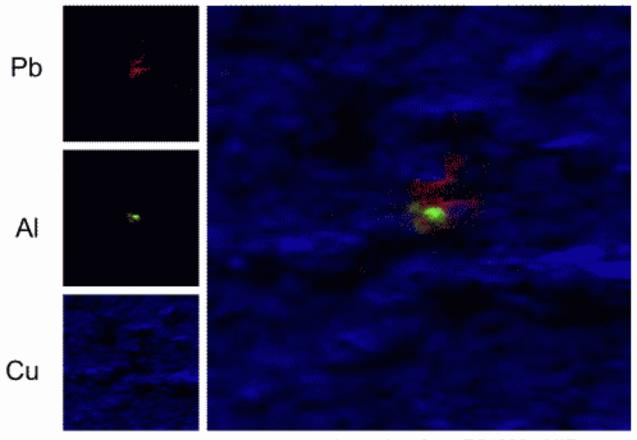
#### Image, Positive Secondary Ion Polarity





Correlation Analysis: 3 Colour Overlay

field of view: 72 x 72 µm<sup>2</sup>



data taken from R54329a.MIF



Measurement Conditions (3D Microarea Analysis)

Instrumentation:

IONTOF "TOF-SIMS IV"

Sputter Erosion:

Ion/Energy: O<sub>2</sub>+, 2 keV

Current: 560 nA

Area: 300 x 300 μm²

Analytical Conditions:

Ion/Energy: Bi<sup>+</sup>, 25 keV

Mode: burst alignment

- Current: 0.2 pA

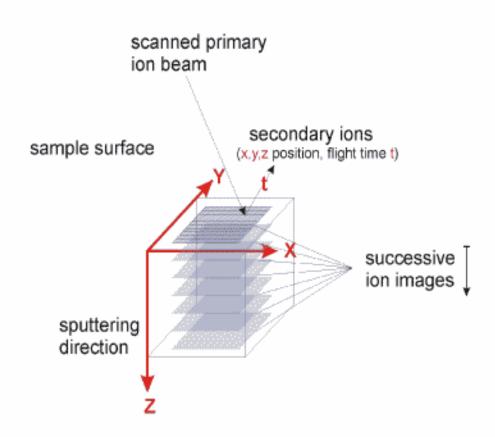
Area: 39 x 39 μm²

 This experiment was performed on the already pre-bombarded area.

### 3D Analysis

#### Analysis Principle



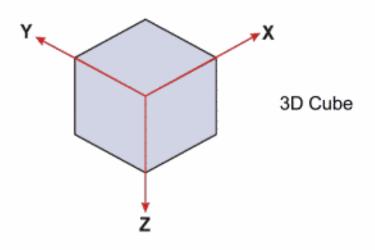


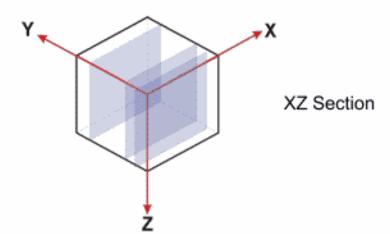
#### Principle of 3D Analysis

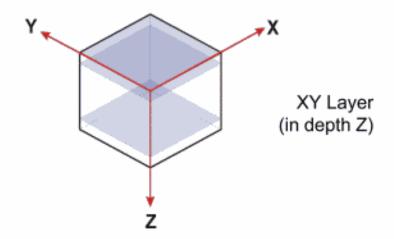
- Combination of SI Imaging and Depth Profiling
- Storage of all detected SI masses as function of cube co-ordinates x, y, z
- Possibility to reconstruct SI images in different depths (XY layers) as well as XZand YZ-cuts

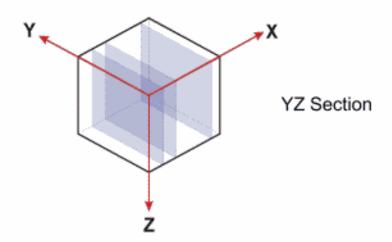
# 3D Analysis

### 3D-Analysis: Co-Ordinates and Cross Sections

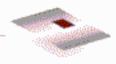




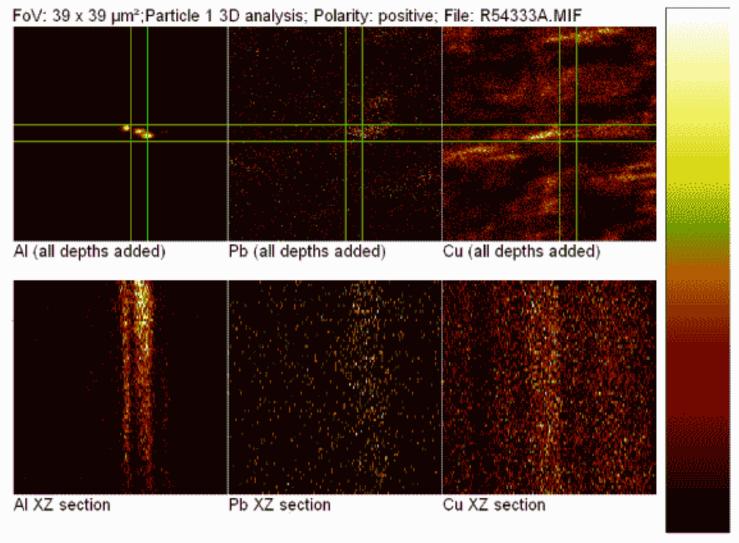




# Particle 1 - 3D Analysis (after Sputt.)



#### Depth Profile, Positive Secondary Ion Polarity



### Particle 1

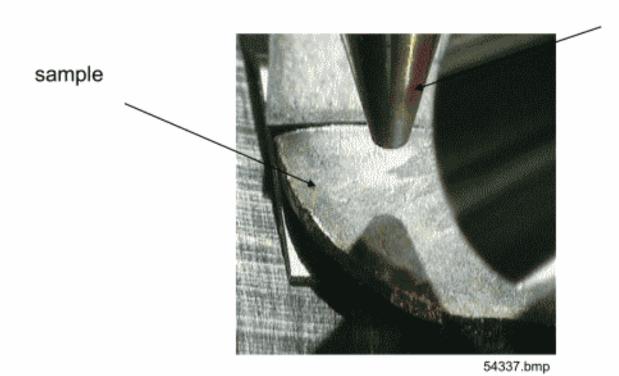
#### Results of Depth Profiling



- In the particle mainly Pb and Al is found. Pb is best visible at the surface whereas the Al intensity is higher in the centre of the particle.
- The Pb containing area is larger than the Al containing area.
- In the centre of the particle additionally B, Si, Ca, Ti, Cr and Fe is found.
- The Al intensity is dropping during the 3D profile (thus the particle was completely sputtered).
- Throughout the complete sputter process a low intensity of Pb prevails.
- It is possible that the pre-analyses (SEM/EDX, Auger) removed some of the particle's surface (Compare results of particle 2).

Optical Image of Sample 232 (Overview)





secondary ion extractor

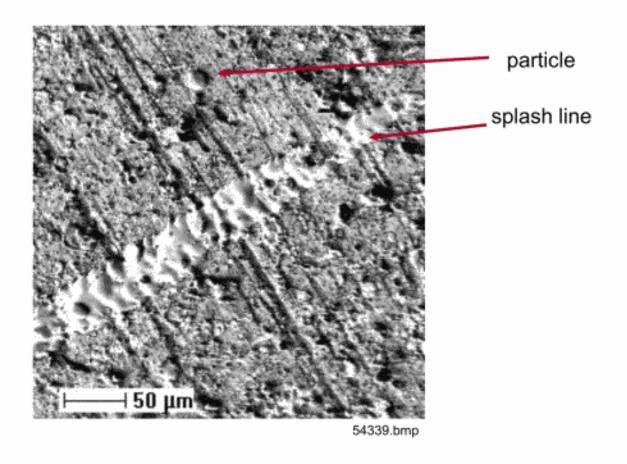


Optical Image of Sample 232 (Detail View Particle 2)

Field of View approx. 700 x 850 µm<sup>2</sup> splash line 54338.bmp

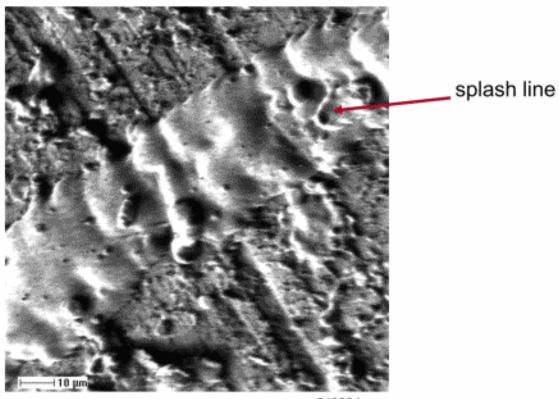
### Ion Induced SE Image





### Ion Induced SE Image

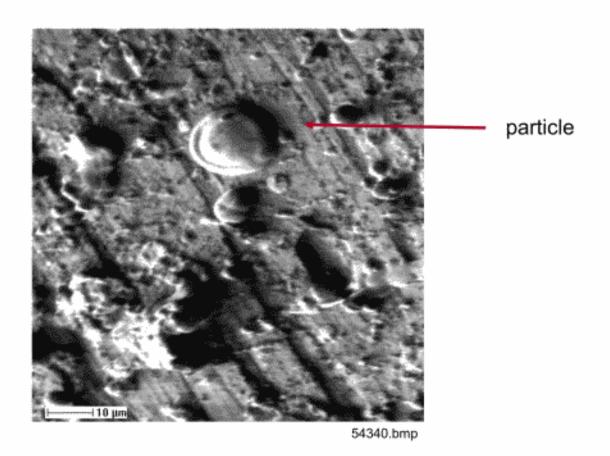




54339.bmp

### Ion Induced SE Image







Measurement Conditions (Surface Imaging)

- Instrumentation:
  - IONTOF "TOF.SIMS 5"
- Analytical Conditions:

Ion / Energy: Bi<sub>1</sub><sup>+</sup>, 25 keV

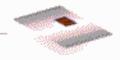
Mode: bunched mode

(high mass resolution,

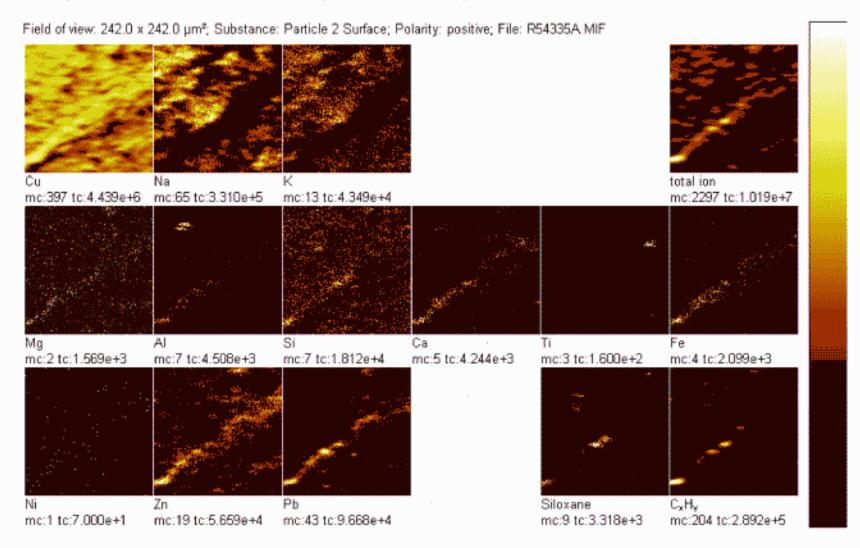
focus approx. 3 µm)

Analysis Current: 0.4 pA

· Area: 242 x 242 μm²



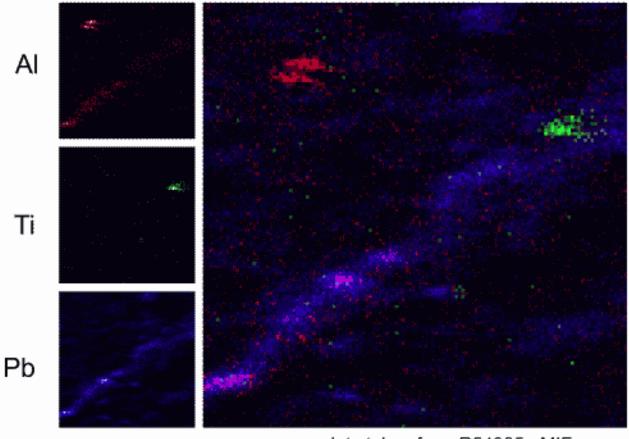
#### Image, Positive Secondary Ion Polarity





Correlation Analysis: 3 Colour Overlay

field of view: 242 x 242 µm²



data taken from R54335a.MIF

### Particle 2

#### Results of Surface Analysis

- The splash line mainyl consists of Cu. Additionally, the elements Mg, Al, Si, Ca, Fe, Ni, Zn and Pb are detected.
- On parts of the splash line organic hydrocarbons and polysiloxane is found. This may be a handling contamination.
- The particle mainly consists of Al.
- Addiontally a position on the splash line is found which is rich in Ti. In the corresponding SE image no particle topography is detected at this position.

#### Disclaimer



- The measurements were performed by specially trained personnel using stateof-the-art instrumentation.
- Nevertheless, we cannot give any guarantee for the correctness of the drawn conclusions.
- We would like to point out that the results refer only to the samples analysed by us.
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